

## M&M 2016 – Vendor Tutorials

Tuesday, July 26, 2016

All tutorials begin at 5:45 PM at respective vendor's booth. Access to exhibit hall via ticket available ONLY at the MSA MegaBooth.

Attolight/Barnett Technical Services	High-resolution quantitative cathodoluminescence (CL) for material science: applications & instrumentation
Bruker	Ultra fast characterization of nanomaterials in the SEM
Bruker	An introduction to Bruker's AMICS software for SEM and $\mu$ XRF
Bruker	Unattended, self-sensing and automated AFM operation with the Dimension FastScan
Carl Zeiss Microscopy, Inc.	Multi-scale Correlative Materials Science: Probing Microstructure Evolution in 3D and 4D , Dr. Nikhilesh Chawla, Arizona State University
Direct Electron, LP	Optimizing Biological Cryo-EM with Direct Electron Cameras
Ephemeron Labs	Quantitative electron beam induced current (EBIC) and analysis
FEI Company	iDPC the new ABF
FEI Company	Obtain the highest quality TEM samples and FIB tomography results faster and easier than ever before.
Gatan	Application of high speed cameras for 4D data collection in STEM
Gatan	Optimizing STEM spectrum image acquisition for high-speed analysis
Hitachi High Technologies America, Inc.	Advanced Low Voltage Imaging and EDS Analysis on the CFE-SEM
HREM Research Inc.	New DM Plug-ins (2)
iLab Solutions, LLC	Implementing a Core Facility Management Leaves More Time for Science
JEOL USA, Inc. & Hummingbird Scientific	In-Situ TEM with Environmental Cell Holders
Kleindiek Nanotechnik	NanoWorkstation, SFAFM, and intuitive TEM sample Prep - micromanipulators in SEM & FIB/SEM
Nanojehm	Aura Workstation Demonstration
Nion	Vibrational Spectroscopy in the STEM
Oxford Nanoimaging	Compact super resolution microscopy
Protochips and FEI	Grace Burke of the University of Manchester will present on: In Situ Corrosion and Electrochemistry: Applications of Advanced Liquid Cell Analytical Electron Microscopy to Steels
Protochips	James M. LeBeau of NC State University will present on direct, in-situ determination of polar SrTiO <sub>3</sub> (110) surfaces at temperatures up to 900 C using cross-sectional aberration corrected STEM to observe the coexistence of various surface structures that change as a function of temperature.
PulseTor LLC	BSE and BSE+CL Hybrid Detectors based on Silicon Photomultiplier (SiPM) Technology
Raith America, Inc.	Large Area, High Resolution SEM Imaging with 3D-Stitching

RMC-Boeckeler

Ted Pella, Inc.

Vitatch Electromagnetics

Ultrastructural Analysis using Automatic Tape-Collecting Ultramicrotome for SEM Array  
Tomography

PELCO BioWave(R) Pro + - Redesigned with the User in Mind

Meeting EMI Compliance for SEM/TEM imaging